

FORM PTO 1449 (modified)
 U.S. DEPARTMENT OF COMMERCE
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APPLICANTS
 Francesco Cerrina, et al.

FILING DATE

GROUP 1631

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AM	4,146,329	3/27/79	King, et al.			
	4,163,150	7/31/79	Stankewitz			
	4,301,363	11/17/81	Suzuki, et al.			
	4,571,603	2/18/86	Hornbeck, et al.			
	4,596,992	6/24/86	Hornbeck			
	4,615,595	10/7/86	Hornbeck			
	4,662,746	5/5/87	Hornbeck			
	5,028,939	7/2/91	Hornbeck, et al.			
	5,096,279	3/17/92	Hornbeck, et al.			
	5,143,854	9/1/92	Pirrung, et al.			
	5,202,231	4/13/93	Drmanac, et al.			
	5,252,743	10/12/93	Barrett, et al.			
	5,318,679	6/7/94	Nichioka			
	5,324,483	6/28/94	Cody, et al.			
	5,405,783	4/11/95	Pirrung, et al.			
	5,412,087	5/2/95	McGall, et al.			
	5,424,186	6/13/95	Fodor, et al.			
	5,445,934	8/29/95	Fodor, et al.			
	5,451,683	9/19/95	Barrett, et al.			
	5,482,867	1/9/96	Barrett, et al.			
	5,489,678	2/6/96	Fodor, et al.			
	5,504,614	4/2/96	Webb, et al.			

AM		5,510,270	4/23/96	Fodor, et al.		
		5,535,047	7/9/96	Hornbeck		
		5,556,752	9/17/96	Lockhart, et al.		
		5,578,832	11/26/96	Trulson, et al.		
		5,583,688	12/10/96	Hornbeck		
		5,593,839	1/14/97	Hubbell, et al.		
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		5,631,734	5/20/97	Stern, et al.		
		5,653,939	8/5/97	Hollis, et al.		
		5,677,195	10/14/97	Winkler, et al.		
		5,695,940	12/9/97	Drmanac, et al.		
		5,744,305	4/28/98	Fodor, et al.		
		5,753,788	5/19/98	Fodor, et al.		
		5,768,009	6/16/98	Little		
		5,831,070	11/3/98	Pease, et al.		

FOREIGN PATENT DOCUMENTS

AM	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
	WO 93/22678	11/11/93	PCT			
	WO 99/41007	8/19/99	PCT			
	EP 0 961 174 A2	12/1/99	EP			
	WO 99/63385	12/9/99	PCT			

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

AM		A. Offner, "New Concepts in Projection Mask Aligners," Optical Engineering, Vol. 14, pp. 130-132 (1975).
		R.T. Kerth, et al., "Excimer Laser Projection Lithography on a Full-Field Scanning Projection System," IEEE Electron Device Letters, Vol. EDL-7(5), pp. 299-301 (1986).
		F.N. Goodall, et al., "Excimer Laser Photolithography with 1:1 Wynne-Dyson Optics," SPIE Vol. 922, Optical/Laser Microlithography, 1988.
		B. Ruff, et al., "Broadband Deep-UV High NA Photolithography System," SPIE Vol. 1088, Optical/Laser Microlithography II (1989).

JM		John A. Neff, et al., "Two-Dimensional Spatial Light Modulators: A Tutorial," Proceedings of the IEEE, Vol. 78, No. 5, May, 1990.
f		Pease, et al., "Light-Generated Oligonucleotide Arrays for Rapid DNA Sequence Analysis," Proc. Natl. Acad. Sci. USA, Vol. 91, pp. 5022-5026, May 1994.
		Larry J. Hornbeck, "Digital Light Processing and MEMs: Reflecting the Digital Display Needs of the Networked Society," SPIE/EOS European Symposium on Lasers, Optics, and Vision for Productivity and Manufacturing I, Besancon, France, June 10-14, 1996.
		McGall, et al., "Light-Directed Synthesis of High-Density Oligonucleotide Arrays Using Semiconductor Photoresists," Proc. Natl. Acad. Sci. USA, Vol. 93, pp. 13555-13560, November 1996.
V		G.H. McGall, et al., "The Efficiency of Light-Directed Synthesis of DNA Arrays on Glass Substrates," Journal of the American Chemical Society 119, No. 22, 1997, pp. 5081-5090.
EXAMINER <i>Adam Mansley</i>	DATE CONSIDERED <i>6-30-03</i>	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant..